

Claim Amendments

1. (currently amended) An apparatus providing identification, monitoring, and tracking of facilities maintenance, comprising:

an interactive information storage device configured for receiving and retaining at least one facility profile, said facility profile including a facility identification, at least one process area descriptor identifying a functional subdivision of a facility, at least one substrate comprising a maintainable item associated with each process area [descriptor], and associated with each substrate a substrate condition having a quantitative value representative of a subjective qualitative assessment of the condition of the substrate, a substrate environment having a quantitative value representative of a subjective qualitative assessment of the environment of the substrate, a substrate process priority having a quantitative value representative of a subjective assessment of the criticality of the substrate to the process area, and a substrate area;

an analyzer for evaluating said quantitative values of the substrate condition, substrate environment, and substrate process priority to determine a quantitative substrate ranking;

an estimator for applying a standard work information to the substrate condition, substrate environment, substrate process priority, and substrate area to determine a substrate maintenance estimate;

a reporter for generating maintenance specifications of the substrate maintenance estimates and substrate ranking for a selected one of the facility profiles.

2. (original) The apparatus as recited in claim 1, wherein said interactive information storage device comprises a remotely located first computer device accessible through an interactive computer network by at least one second computer device associated with said facility profile.

3. (original) The apparatus as recited in claim 1, further comprising a substrate maintenance specification associated with each different type of substrate, said substrate maintenance specification comprising at least a maintenance purpose, a maintenance preparation, and a maintenance coating, for specifying maintenance tasks and bidding thereon.

4. (original) The apparatus as recited in claim 3, further comprising a bid generator for preparing maintenance services requests based on selected substrates and said associated substrate maintenance specification.

5. (original) The apparatus as recited in claim 1, further comprising at least one substrate maintenance history for at least one of said substrates, each substrate maintenance history comprising a job identification, a job notes, and a job cost, for tracking maintenance projects for said substrate.

6. (original) The apparatus as recited in claim 1, wherein said reporter generates an evaluation for a selected one of the substrates based on said substrate maintenance history and said substrate maintenance estimate.

7. (original) The apparatus as recited in claim 1, wherein said substrate further comprises a substrate factor based on said substrate maintenance history.

8. (currently amended) A method for identifying, monitoring, and tracking of facilities maintenance, comprising the steps of:

(a) subdividing a facility into separate process areas representative of functional subdivisional areas of the facility;

(b) identifying within each process area at least one substrate comprising a maintainable item associated with the process area together with a substrate condition having a quantitative value representative of a subjective qualitative assessment of the substrate condition, a substrate environment having a quantitative value representative of a subjective qualitative assessment of the substrate environment, and a substrate process priority having a quantitative value representative of a subjective assessment of the criticality of the substrate to the process area;

(c) analyzing the substrate condition, substrate environment, and substrate process priority to determine a quantitative substrate ranking;

(d) generating maintenance specifications using a substrate maintenance estimates and substrate ranking for a selected one of the facilities.

9. (original) The method as recited in claim 8, further comprising the step of maintaining the process area and substrate information on an interactive information storage device.

10. (original) The method as recited in claim 9, where maintenance specifications performed on substrates revise the substrate information contained on the interactive information storage device.

11. (original) The method as recited in claim 10, wherein the interactive information storage device is operated by a remote first computer device accessed through an interactive computer network by at least one second computer device associated with said facility.

12. (original) The method as recited in claim 1, further comprising the step of providing at least one substrate maintenance specification associated with each different type of substrate, said substrate maintenance specification comprising at least a maintenance purpose, a maintenance preparation, and a maintenance coating, for specifying maintenance tasks and bidding thereon.

13. (original) The method as recited in claim 12, further comprising the step of generating maintenance bid specifications for obtaining maintenance services based on selected substrates and said associated substrate maintenance specification.

14. (original) The method as recited in claim 13, further comprising the steps of completing at least one substrate maintenance project, copying the prior information about the substrate to a substrate history, and editing the substrate information to reflect changes based on the maintenance project.

15. (original) The method as recited in claim 14, further comprising for at least one of said substrates, the steps of maintaining in each substrate maintenance history a job identification, a job notes, and a job cost, for tracking maintenance projects for said substrate.

16. (currently amended) The [apparatus] method as recited in claim 8, comprising the step of generating an evaluation for a selected one of the substrates based on said substrate maintenance history and said substrate maintenance estimate.

17. (new) The method as recited in claim 8, wherein step (c) analyzing further comprises the assigning a separate percentage to each of the substrate condition, substrate environment, and substrate priority, said percentages totaling 100 percent, to determine the substrate ranking.

18. (new) The apparatus as recited in claim 1, wherein the analyzer assigns a separate percentage to each of the substrate condition, substrate environment, and substrate priority, said percentages totaling 100 percent, to determine the substrate ranking.